What is claimed is:

1. An electrostatic chuck having a bonded structure comprising a ceramic electrostatic chuck member, a metal member, and a bonding layer; said ceramic electrostatic chuck member and the metal member being bonded with said boding layer,

wherein said bonding layer has at least a first most outer bonding layer being bonded to said ceramic electrostatic chuck member, a second most outer bonding layer being bonded to said metal member, and a polyimide layer being disposed between said first and second most outer bonding layers, and each of most outer bonding layers is made of either a silicone layer or an acrylic layer.

2. The electrostatic chuck according to claim 1, wherein the thickness of the bonding layer is 0.05 to 0.5 mm.

3. The electrostatic chuck according to claim 1, wherein the ceramic electrostatic chuck member has a base material made of aluminum nitride, and said base material is being formed as an integrated body by sintering it with an electrostatic chuck electrode being embedded thereinto.

4. The electrostatic chuck according to claim 1, wherein flatness of an adsorption surface in the ceramic electrostatic chuck member is 30 μm or less.

5. A method for manufacturing an electrostatic chuck having a bonded structure comprising a ceramic electrostatic chuck member, a metal member, and a bonding layer; said ceramic electrostatic chuck member and the metal member being bonded with said boding layer,

wherein said bonding layer has at least a first most outer bonding layer being bonded to said ceramic electrostatic chuck member, a second most outer bonding layer being bonded to said metal member, and a polyimide layer being disposed between said first and second most outer bonding layers, and each of most outer bonding layers is made of either a silicone layer or an acrylic layer;

wherein said method comprises the steps of:

preparing a sheet comprising at least a first most outer layer, second most outer layer made of either a silicone layer or an acrylic layer, and an intermediate layer being disposed between said first and second most outer layers and made of a polyimide layer,

vacuum-packing said electrostatic chuck member, said bonding layer, said metal layer and said sheet being sandwiched between said electrostatic chuck member and said metal member into a vacuum-packing bag; and

heating thus vacuum-packed electrostatic chuck member, bonding layer and metal layer under isotropic pressurization to bond them firmly.